IN THE CLAIMS:

Please note that, pursuant to 37 CFR 1.121(c)(3), all claims currently pending and under consideration in the referenced application are shown below, in clean form, for clarity and for the convenience of the Patent Office. Also attached is a version with markings to show changes made to the claims.

Please cancel claims 6 and 14 through 37 without prejudice or disclaimer.

Please amend claims 1, 2, 4, 5 and 7 through 13 as set forth below.

1. (Twice Amended) A deposition chamber comprising:

a chamber body having a cavity formed therein;

a chamber lid configured to enclose the cavity;

a vapor delivery head positioned within the cavity;

a feedthrough device positioned in the chamber body, the feedthrough device having a longitudinal body portion and being configured to receive vapor from a vapor source and transfer the vapor therethrough along a pathway toward the vapor delivery head;

a heating device including a pair of resistor elements having at least a portion thereof disposed within a thermally conductive sheathing, the heating device including a first, nonheated section and a second, heated section, wherein at least a portion of the second heated section is configured to conduct heat to the longitudinal body portion of the feedthrough device;

a layer of thermal insulation disposed between the at least a portion of the second, heated section of the heating device and the chamber body and substantially circumscribing the longitudinal body portion and the at least a portion of the second, heated section; and

a temperature sensing device disposed between the layer of insulation and the longitudinal body portion of the feedthrough device.

2. (Previously Amended) The deposition chamber of claim 1, wherein the feedthrough device includes a lumen defined therethrough for transferring the vapor therethrough.

3. (Amended) The deposition chamber of claim 2, wherein the feedthrough device includes a continual helical groove formed on a surface of the longitudinal body portion.

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4. (Twice Amended) The deposition chamber of claim 3, wherein the at least a portion of the second, heated section is disposed within the continual helical groove of the feedthrough device.

5. (Twice Amended) The deposition chamber of claim 4, wherein the continual helical groove is configured to complementarily receive the at least a portion of the second heated section.

7. (Amended) The deposition chamber of claim 1, wherein the thermally conductive sheathing is formed of stainless steel.

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8. (Amended) The deposition chamber of claim 1, wherein the temperature sensing device is disposed within the thermally conductive sheath.

9. (Twice Amended) The deposition chamber of claim 1, wherein the temperature sensing device includes a thermocouple.

10. (Amended) The deposition chamber of claim 9, wherein the thermocouple is positioned within the thermally conductive sheathing.

11. (Twice Amended) The deposition chamber of claim 1, wherein at least a portion of the thermally conductive sheathing is cold formed into a helical pattern complementary with the continual helical groove.

12. (Amended) The deposition chamber of claim 1, wherein at least a portion of the thermally conductive sheathing is adhered to the feedthrough device.

13. (Amended) The deposition chamber of claim 1, wherein at least a portion of the thermally conductive sheathing is welded to the feedthrough device.